



Revised 05/01/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Yixiang Duan

Docket No.: S-100,580

Serial No.: 10/616,610

Examiner:

Filed : 7/9/2003

Art Unit:

For : LOW-POWERED ATMOSPHERIC PRESSURE MINI-PLASMA
AND ARRAY FOR SURFACE AND MATERIAL TREATMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR 1.56, 1.97, AND 1.98

Sir:

The documents listed below, copies attached, are submitted in compliance with the duty of disclosure defined in 37 CFR 1.56.

1. Yixiang et al., "Pulsed, Atmospheric Pressure Plasma Source for Emission Spectrometry," US Patent Application, SN: 09/998,273, Filed November 30, 2001.
2. Spangler, "Ion Mobility Storage Trap and Method," US Patent 6,124,592, Issued, September 26, 2000.

CERTIFICATE OF MAILING/TRANSMISSION (37 CFR 1.8(a))

I hereby certify that this correspondence is, on the date shown below, being:

MAILING

☒ deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to the:
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Signature

Mark N. Fitzgerald
(type or print name of person certifying)

Date

9/29/03

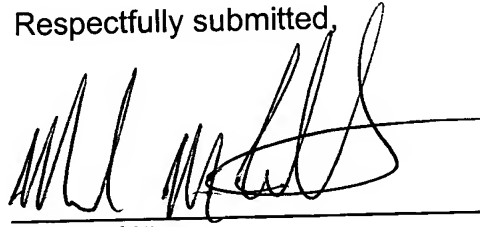
This Information Disclosure Statement is not to be construed as a representation that a search has been made or that additional matter material to the examination of this application does not exist. Applicant does not believe that any of these citations constitutes prior art under 35 U.S.C. 102.

It is requested that the above citations be made of record in the prosecution of this application.

Date: 9/29/03

Reg. No. 48,300
Phone (505) (505) 665-5187

Respectfully submitted,



Signature of Attorney

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Form PTO-1449
(Modified)U.S. Department of Commerce
Patent and Trademark Office

Attorney Docket No.

S-100,580

Serial No.

10/616,610

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

Applicant(s)

Yixiang Duan

Filing Date
7/9/2003

Group

37 CFR 1.98(b)

U.S. PATENTS DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER								ISSUE DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
		6	1	2	4	5	9	2	09/26/00	Spangler	250	287	03/18/98

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER								ISSUE DATE	COUNTRY	CLASS	SUB CLASS	Translation YES NO	

OTHER DOCUMENTS (Including Author, Title, Date, Place of Publication)

Yixiang et al., "Pulsed, Atmospheric Pressure Plasma Source for Emission Spectrometry," US Patent Application, SN: 09/998,273, Filed November 30, 2001.

EXAMINER:

DATE CONSIDERED:

*EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.